



**FLEXTURA® CLUSTER**  
WHEN THIN FILM MATTERS

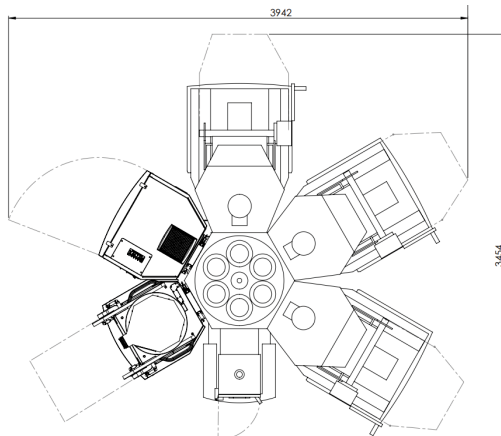
# FLEXTURA®

## 200 CLUSTER

The Flextura® Cluster platform is probably the most flexible 200mm cluster tool available. It is truly almost Plug&Play and you may add process modules as your need for capacity or new processes increase.

### DRIVEN BY UNIQUE PROCESSES

- CSM sputtering (DC, RF, pDC, and HiPIMS)
- Multi magnetron chamber (co-sputtering)
- Automated glancing angle deposition on 200mm wafers
- E-beam evaporation
- Remote Plasma Sputtering technology
- RF/ICP etch, degas, cooling, alignment
- Single wafer or batch processing directly from cassette-to-cassette



### FLEXIBILITY AND RELIABILITY IS KEY

- Scalable capacity from medium to high volume production
- Fully modularised platform – from single chamber to cluster
- Up to 200mm wafers
- Combinations of sputtering and e-beam
- Strong reliable 24/7 production tools
- Fully automated process control with advanced data logging
- SECS/GEM, MES integration optional
- CMOS compatible



# FLEXTURA®

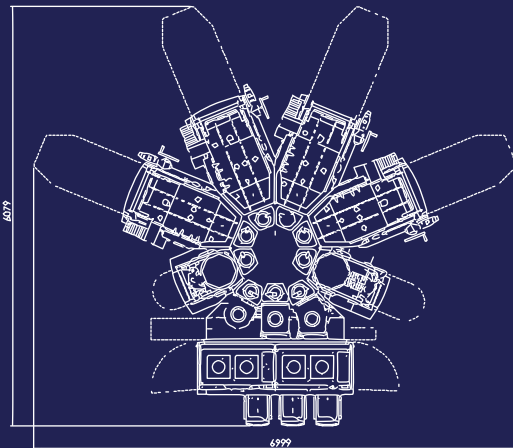
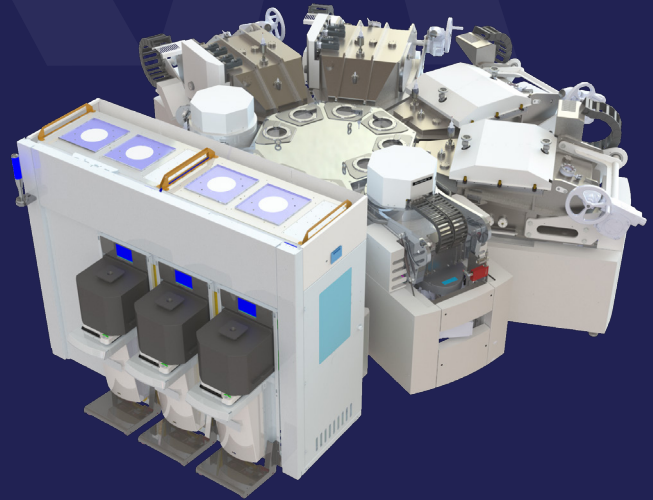
## 300 CLUSTER

### Introducing the Flextura® 300 Cluster tool

Building on the expertise gained from our Flextura® 200 Cluster, this highly reliable PVD platform is an excellent choice for deposition of metals, oxides, and nitrides to produce high quality thin films. Utilising the flexibility of the Flextura® platform the Flextura® 300 Cluster allows customer to optimise the configuration to best fit their applications.

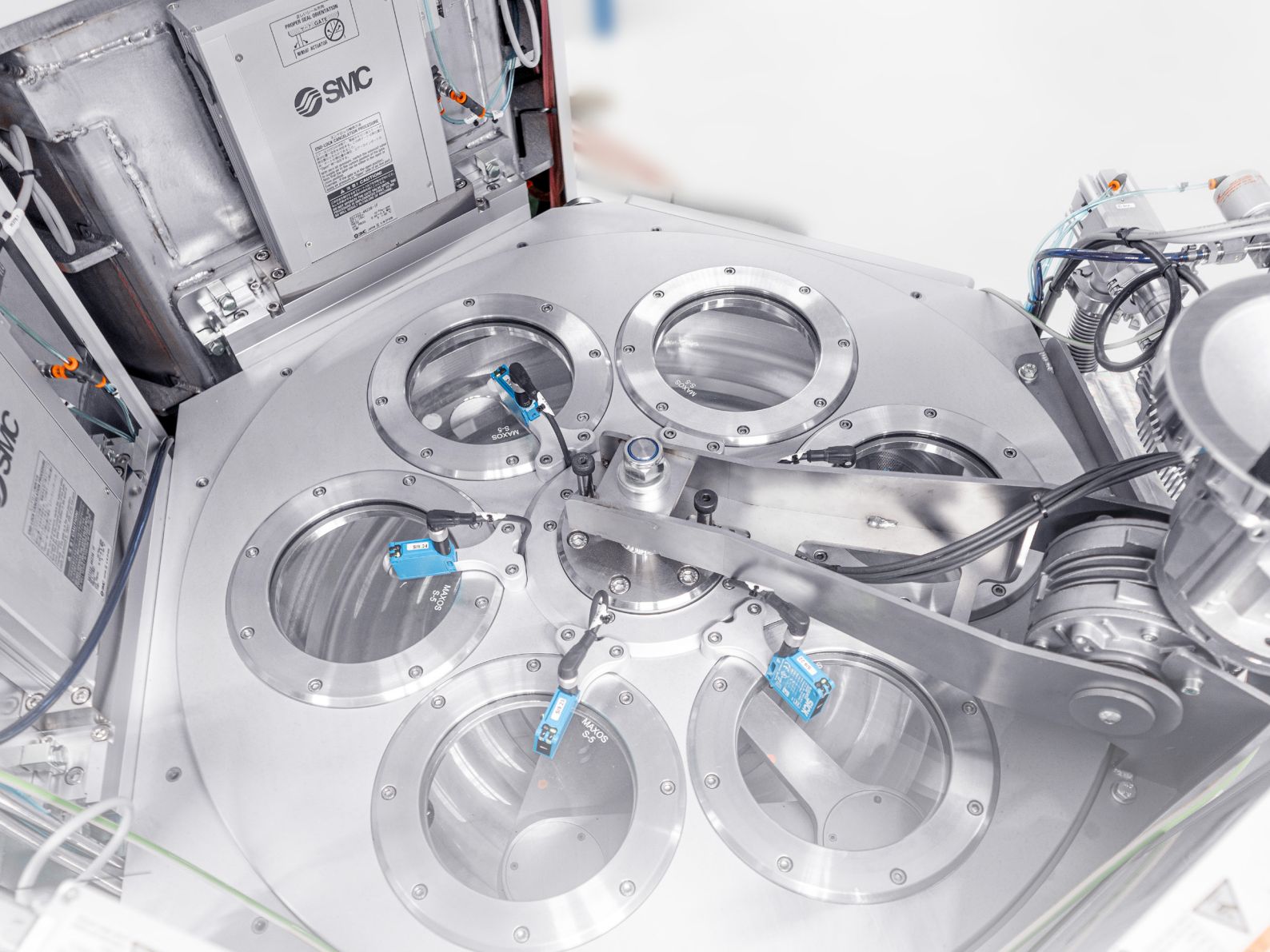
### PROCESS MODULES

- CSM sputtering (HiPIMS, DC, RF, and pDC)
- Linear magnetron sputtering
- Multi magnetron chamber (co-sputtering)
- RF/ICP pre-clean
- Degas, cooling, alignment, buffer station
- Evaporation modules
- Glancing angle deposition



### FLEXTURA 300 CLUSTER PLATFORM HIGHLIGHTS

- Atmospheric front-end with Brooks JCP EFEM
- Up to four Vision™ Leap load ports supporting 300mm FOUF loading
- Substrate heating up to 950°C
- Wafer aligner, wafer mapping, cross-slot detection
- Transfer module with proven reliable wafer handling by Brooks Magnatron LEAP dual arm robot for maximum throughput and reliability
- Up to 6 process modules
- GEM300 compliant communication
- CMOS compatibility



## WHO ARE WE

Polyteknik AS is a PVD equipment manufacturer with an innovative and best service approach. With more than 25 years in business, a global reference list, and an excellent platform of technology, Polyteknik AS has turned to be an appreciated partner in the thin film industry.

## WHAT DO WE DO

The portfolio of platform systems ranges from small scale R&D to high volume or large area deposition systems. Polyteknik AS covers several deposition processes with our Flextura 200 and 300 Cluster, Tornado, and Infinity platforms. At Polyteknik AS you will meet a dedicated team interested in a strong co-operation towards the best solution.

**POLYTEKNIK** 

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